



CANADA'S NATIONAL LABORATORY FOR PARTICLE AND NUCLEAR PHYSICS

*Owned and operated as a joint venture by a consortium of Canadian universities
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Charge State Boosters for Radioactive Ion Acceleration

F. Ames

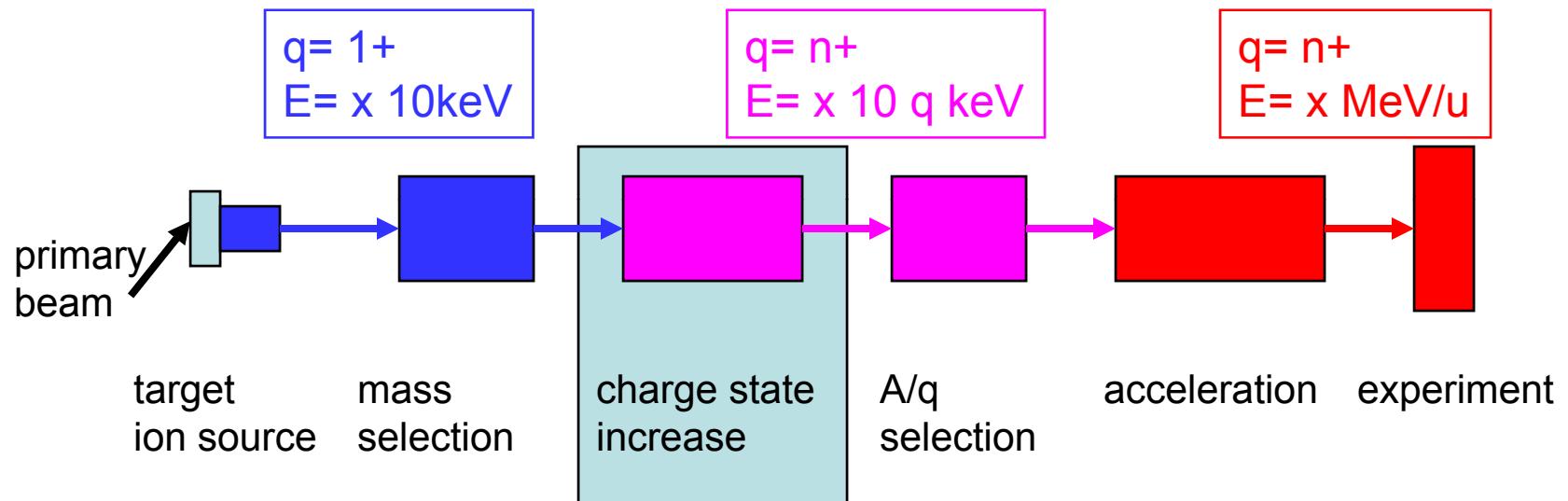
1. Introduction
2. State of the art charge breeding with EBIS and ECRIS
3. Future developments
4. Conclusion and Summary

LINAC08, Victoria, October 2, 2008

LABORATOIRE NATIONAL CANADIEN POUR LA RECHERCHE EN PHYSIQUE NUCLÉAIRE ET EN PHYSIQUE DES PARTICULES

*Propriété d'un consortium d'universités canadiennes, géré en co-entreprise à partir d'une contribution
administrée par le Conseil national de recherches Canada*

acceleration of radioactive ions at an ISOL facility:

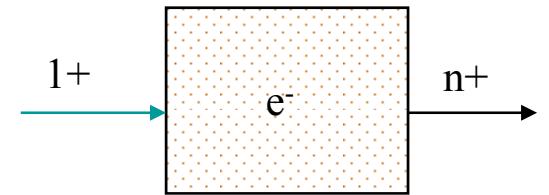


methods for charge state increase:

passive

- stripping after first acceleration
(ISAC I)

simple, fast, high efficiency for light ions,
pure beams
low efficiency for heavy ions

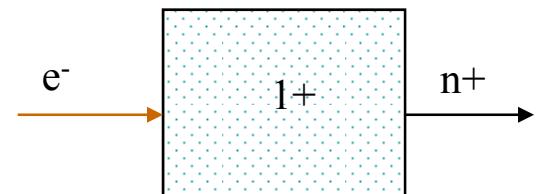


fast 1^+ ions
slow electrons

active

- charge state breeding with an EBIS
(REX-ISOLDE, MSU, GSI,...)
- charge state breeding with an ECRIS
(ISAC II, GANIL, KEK-JAERI, ANL,...)

high charge states, works for all masses
complicated, slow,
background from residual gases



fast electrons
slow 1^+ ions

charge state evolution in EBIS or ECRIS

system of rate equations

only changes by one charge are considered

$$\frac{dn_i}{dt} = n_e v_e \left[\sigma_{i-1 \rightarrow i}^{ion} n_{i-1} - (\sigma_{i \rightarrow i+1}^{ion} + \sigma_{i \rightarrow i-1}^{RR}) n_i + \sigma_{i+1 \rightarrow i}^{RR} \right]$$
$$- n_0 v_{ion} \left[\sigma_{i \rightarrow i-1}^{chex} n_i - \sigma_{i+1 \rightarrow i}^{chex} n_{i+1} \right]$$
$$- v_i^{coll} \frac{\exp\left\{-\frac{ieU_w}{kT_{ion}}\right\}}{-\frac{ieU_w}{kT_{ion}}} n_i$$

n_e , n_i , n_0

density of electrons, ions with charge i and neutrals

v_e , v_i

velocity of electrons and ions

σ^{ion} , σ^{RR} , σ^{chex}

cross section for ionization, radiative recombination and charge exchange

v^{coll}

coulomb collision frequency

T_{ion}

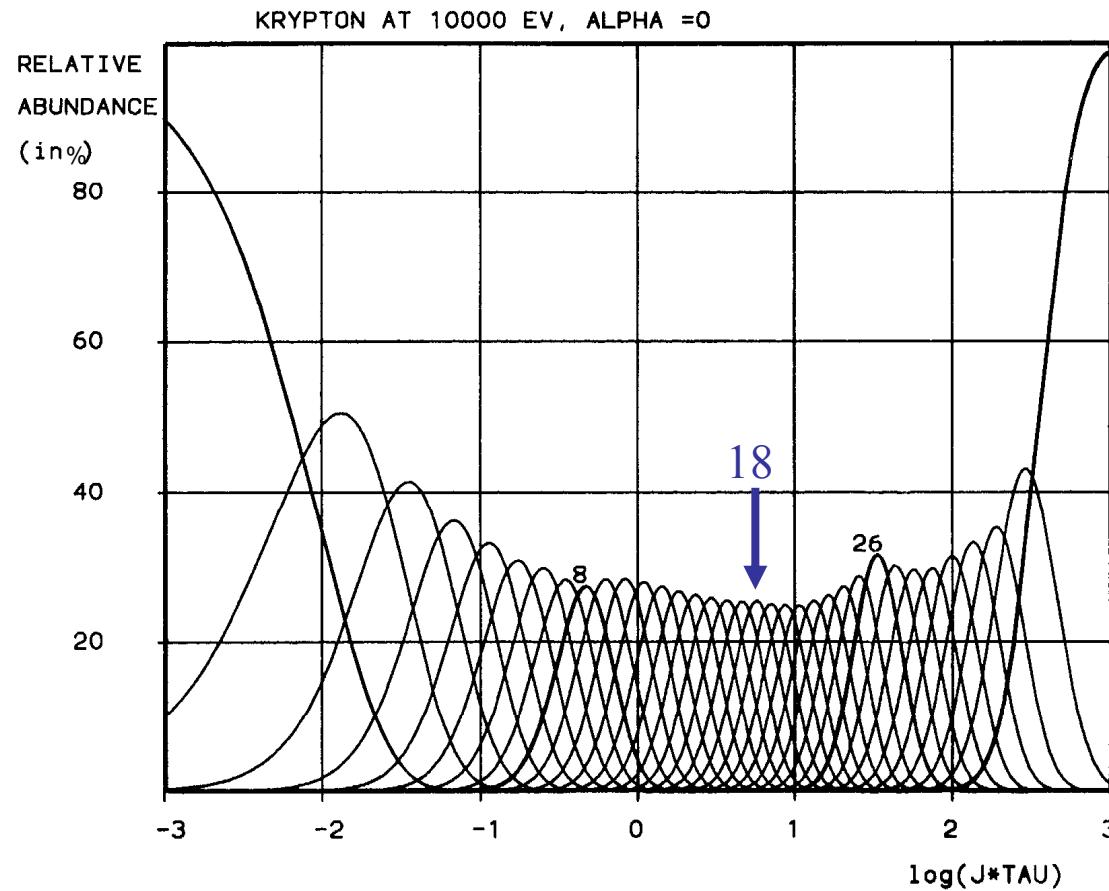
ion temperature

U_w

electrostatic trapping potential

in an ECRIS electron energy distribution function has to be known

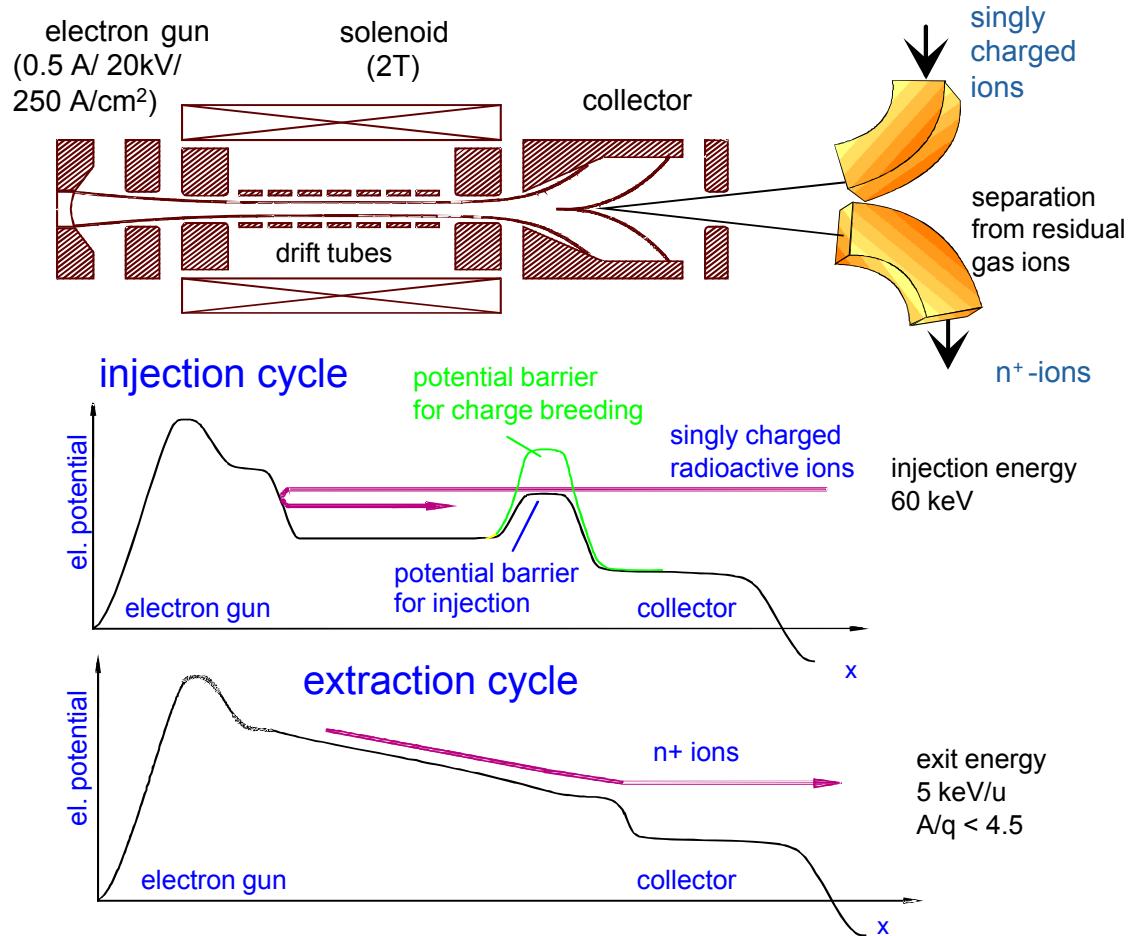
charge state breeding of Krypton in an EBIS



A=84
q=18
 $\Rightarrow q/A = 0.21$

 $j = 250 \text{ A/cm}^2$
 $\tau = 19 \text{ ms}$

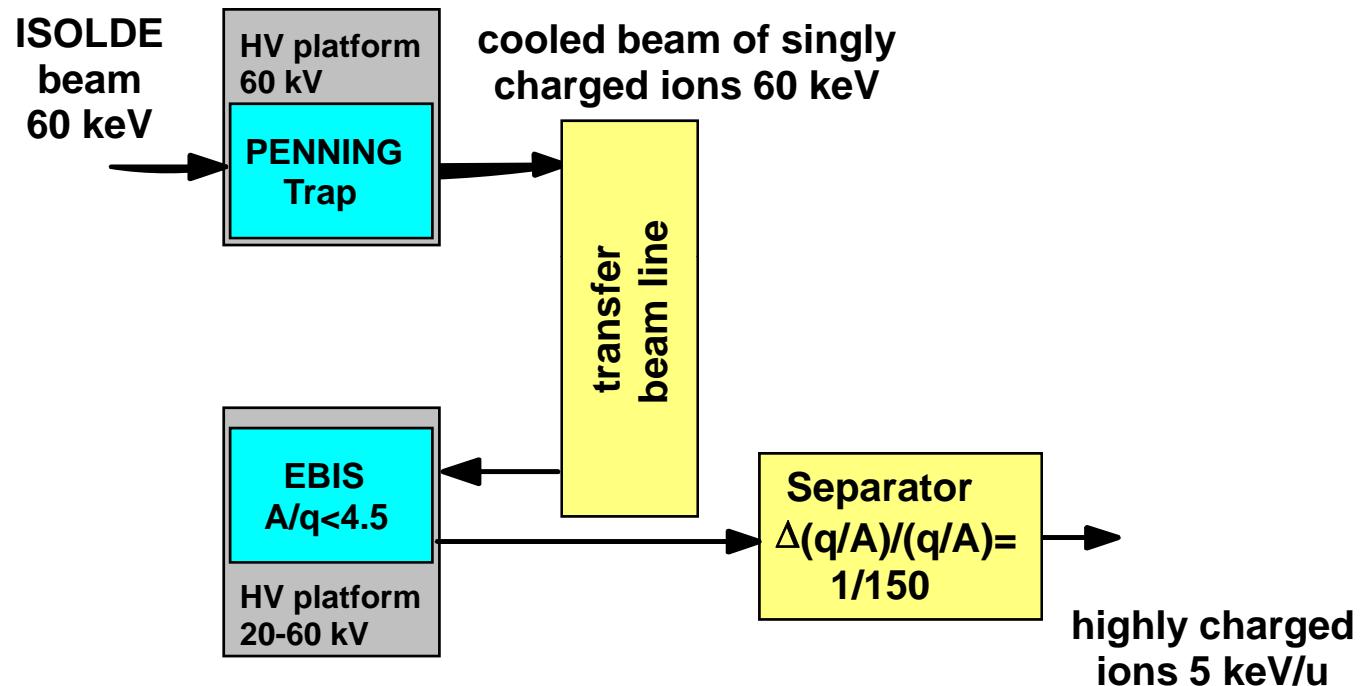
Electron Beam ion source (EBIS)



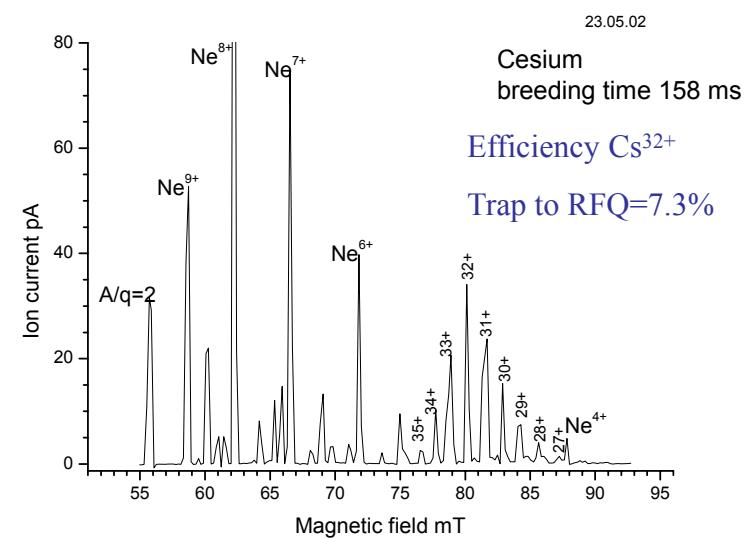
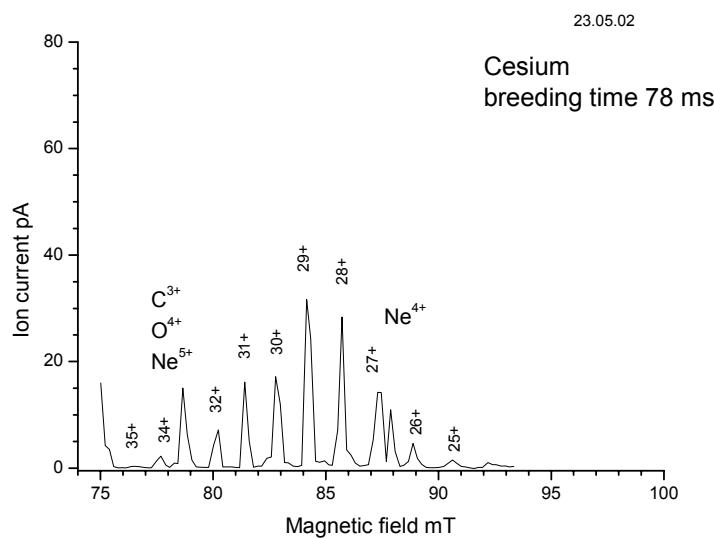
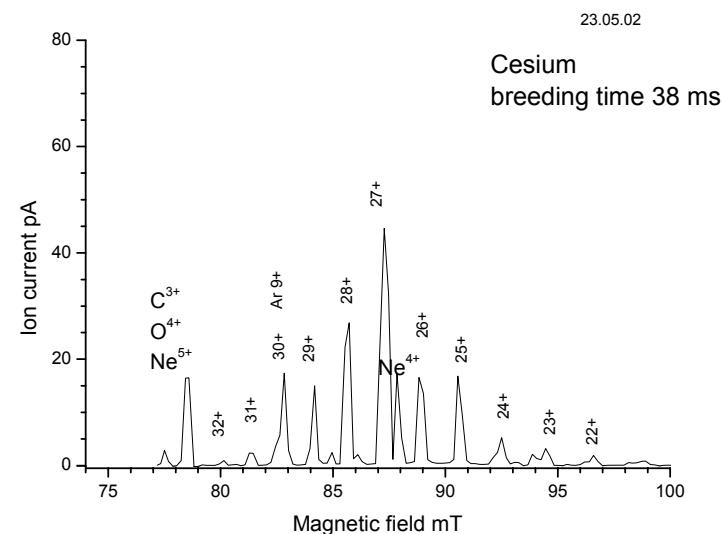
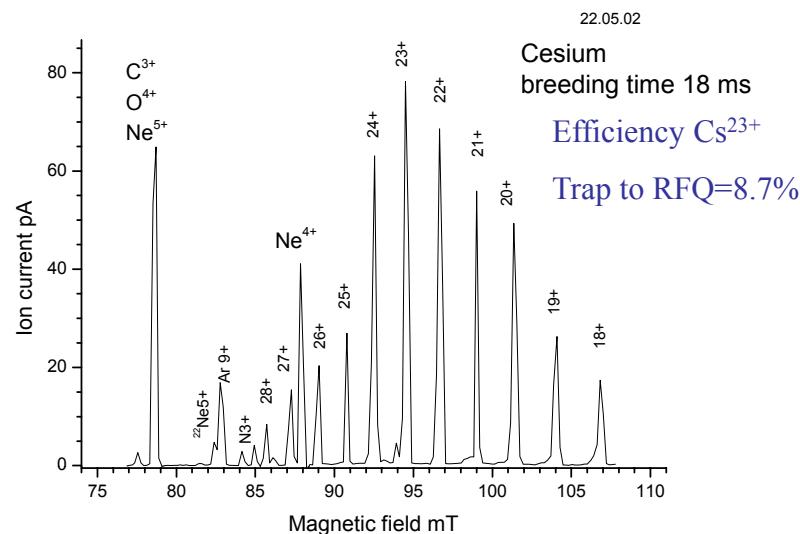
REXEBIS (ISOLDE – CERN)

requires cooling and bunching of incoming beam (REXTRAP)

REXTRAP/REXEBOIS charge breeding system



Charge breeding of ^{133}Cs



A selection of elements charge bred during the 2006 measurement campaign

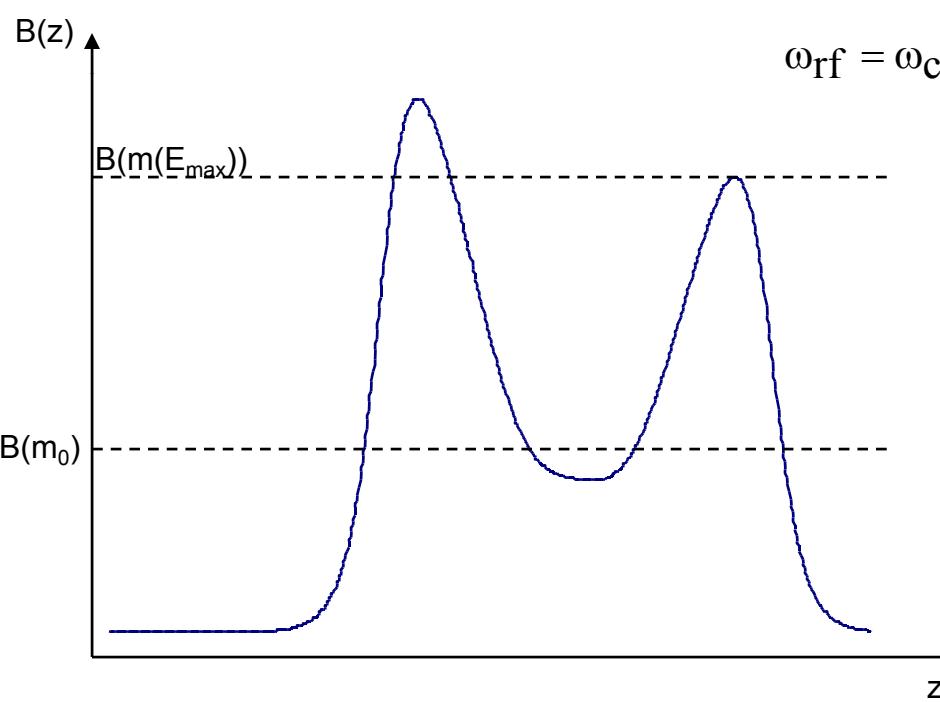
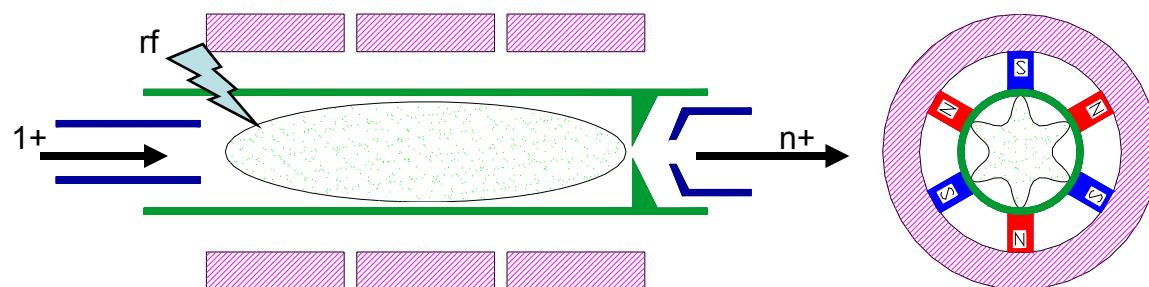
Element	A/q	Total eff. (%)	$T_{\text{cool}} + T_{\text{breed}}$ (ms)	Comments	
$^7\text{Li}^{3+}$	2.333	6.0	20 + 18	Stable	
$^9\text{Li}^{3+}$	3.000	5.0	50 + 15	Radio	Low rep rate due to linac
$^{10}\text{Be}^{3+}$	3.333	5.0	50 + 15	Radio	Low rep rate due to linac
$^{19}\text{F}^{5+}$	3.800	7.8	20 + 7	Stable	
$^{23}\text{Na}^{9+}$	2.555	10.0	30 + 28	Stable	
$^{27}\text{Al}^{7+}$	3.857	>15	20 + 10	Stable	Injected to EBIS as AlF+ molecule
$^{29}\text{Mg}^{9+}$	3.222	6.0	30 + 28	Radio	Very large error bars
$^{39}\text{K}^{10+}$	3.900	15.0	20 + 12	Stable	
$^{65}\text{Cu}^{19+}$	3.421	11.1	100 + 68	Stable	
$^{65}\text{Cu}^{20+}$	3.250	7.8	100 + 68	Stable	Too short breeding time
$^{67}\text{Cu}^{19+}$	3.526	12.6	100 + 68	Radio	
$^{68}\text{Zn}^{21+}$	3.238	12.4	80 + 78	Stable	For 80Zn21+
$^{71}\text{Cu}^{20+}$	3.550	11.0	100 + 98	Stable	Large error → overestimated?
$^{116}\text{Cd}^{31+}$	3.742	9.6	250 + 248	Stable	For 124Cd30+ and 126Cd31+ run
$^{133}\text{Cs}^{33+}$	4.030	10.8	200 + 198	Stable	For 124Cd30+ and 126Cd31+ run
$^{136}\text{Xe}^{34+}$	4.000	8.7	200 + 198	Stable	For 144Xe34+ run
$^{181}\text{Ta}^{40+}$	4.525	2.9	200 + 198	Stable	Not optimum tuning
$^{238}\text{U}^{52+}$	4.577	4.3	500 + 498	Stable	

The total efficiency is the combined REXTRAP + REXEBIS + mass separator efficiency.

bunching and cooling efficiency $\approx 50\%$

F. Wenander, NIM B (2008) in press

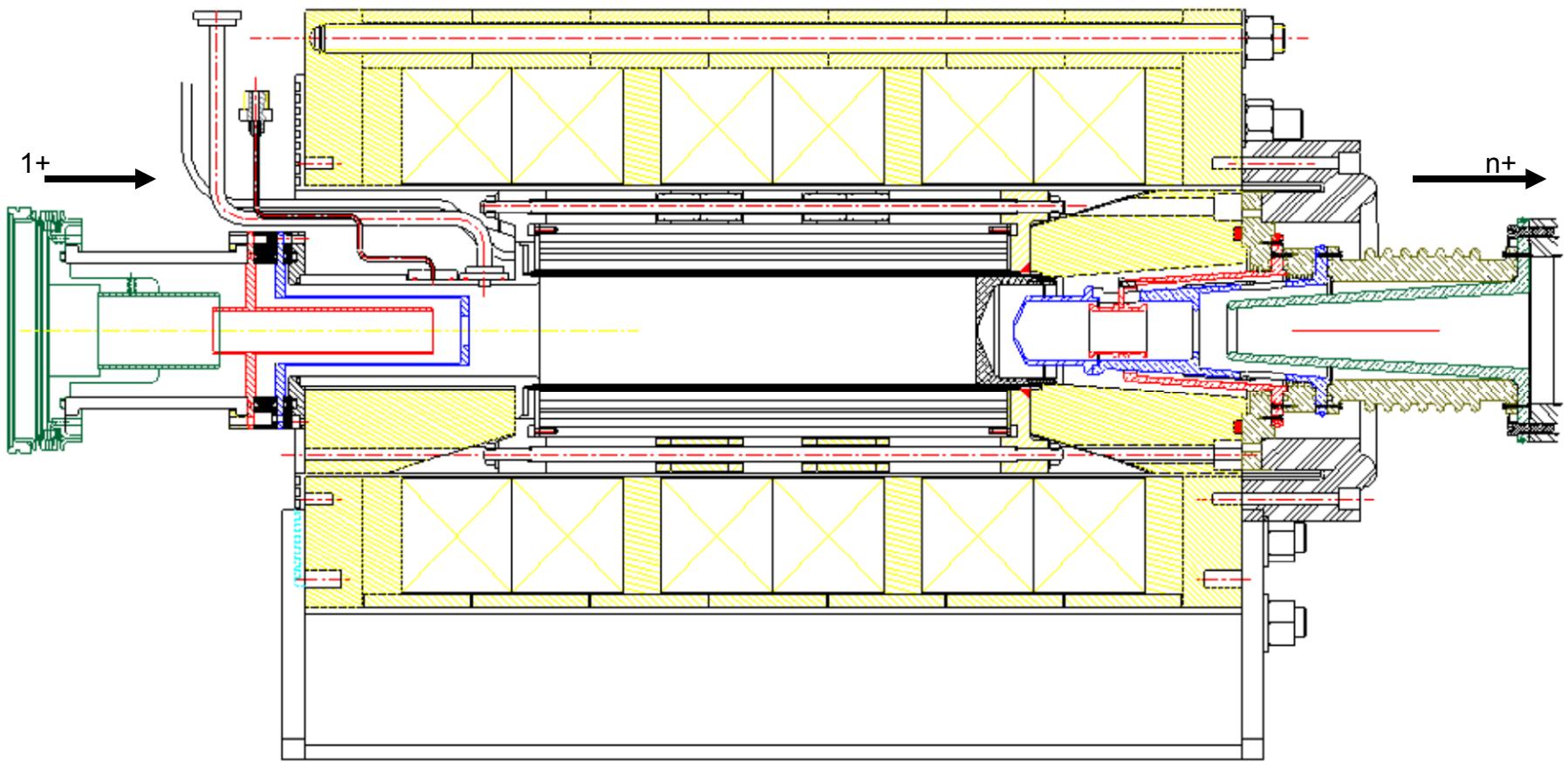
Electron Cyclotron Resonance Ion Source (ECRIS)



$$\omega_{rf} = \omega_c = \frac{q}{m(E)} B$$

PHOENIX ECR source:
 $v_{rf} = 14.5 \text{ GHz}$
 $\Rightarrow B(m_0) = 0.52 \text{ T}$
 $B_{\max} = 1.25 \text{ T}$
 $\Rightarrow E_{\max} = 730 \text{ keV}$
 $n_e = 10^{11} \dots 10^{12} \text{ cm}^{-3}$





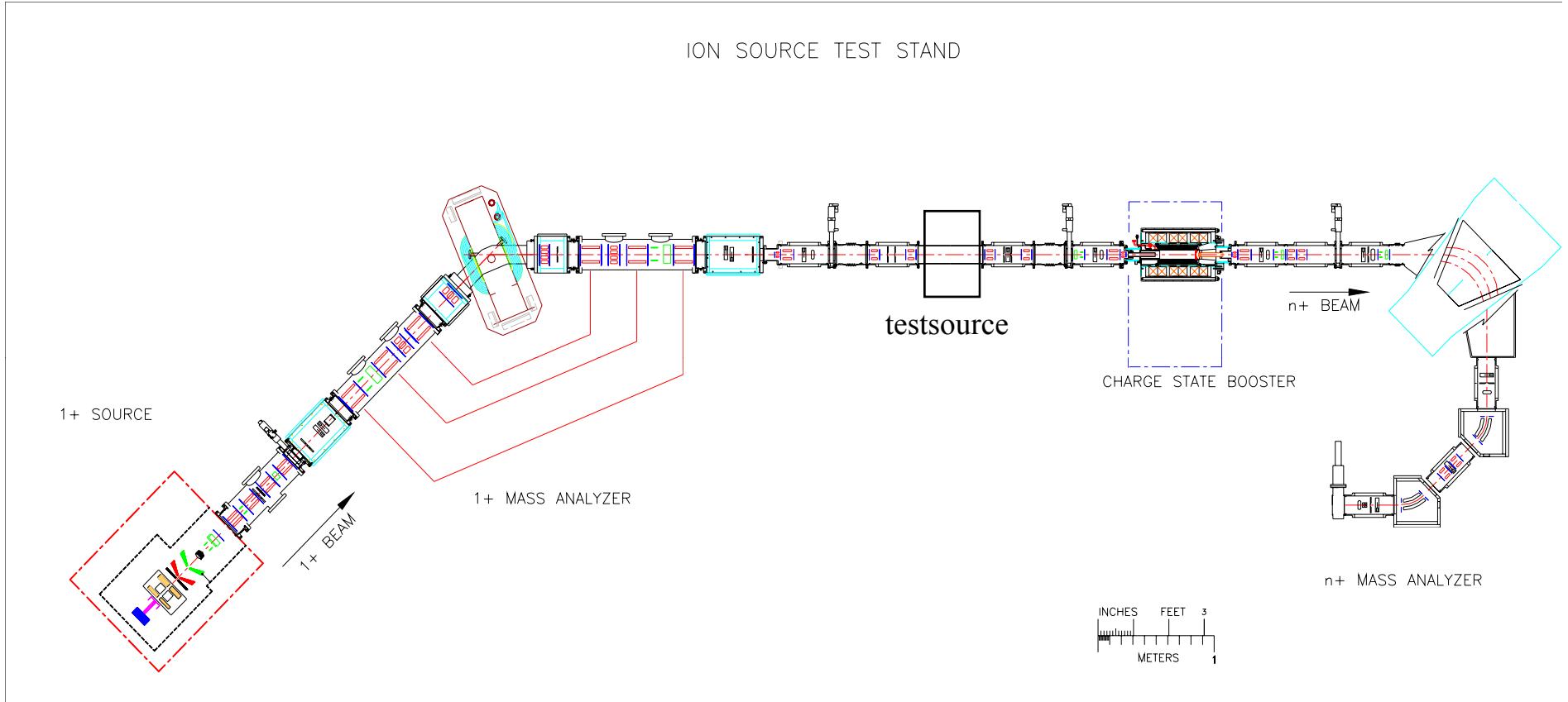
modified PHOENIX source for ISAC

2 step deceleration for the injection of singly charged ions

2 step acceleration scheme + Einzel lens focusing

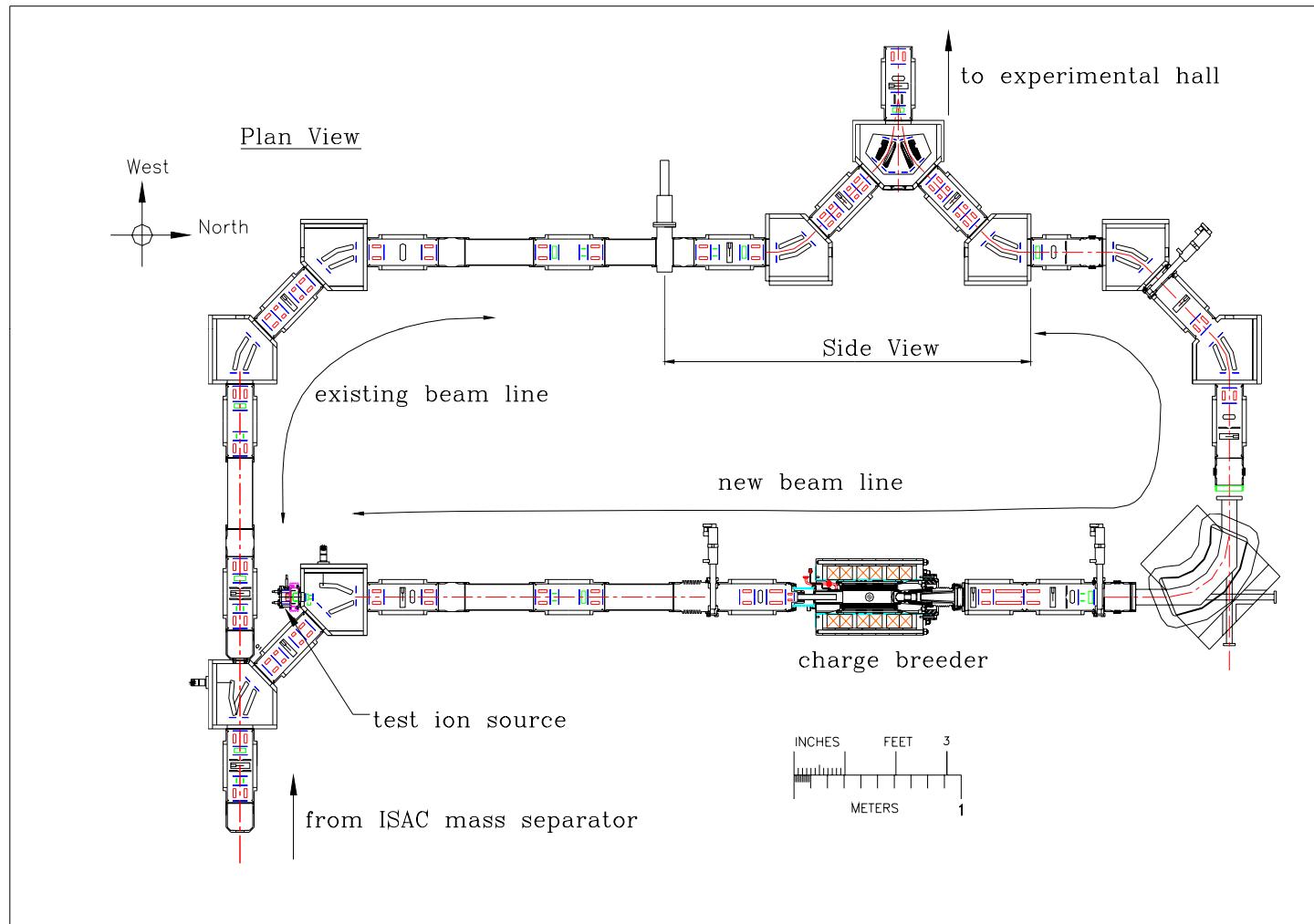
for the extraction of the highly charged ions

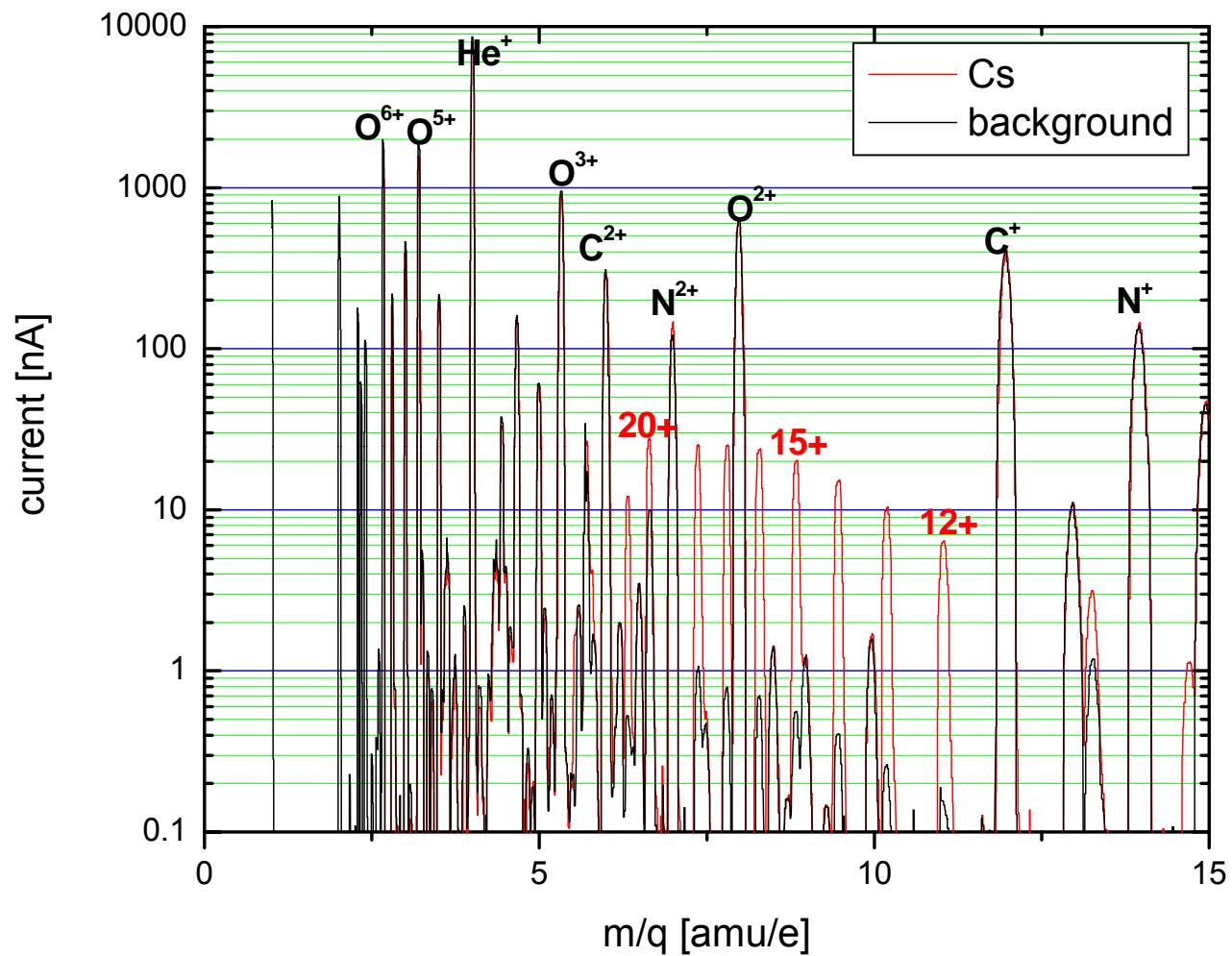
CSB test stand at TRIUMF



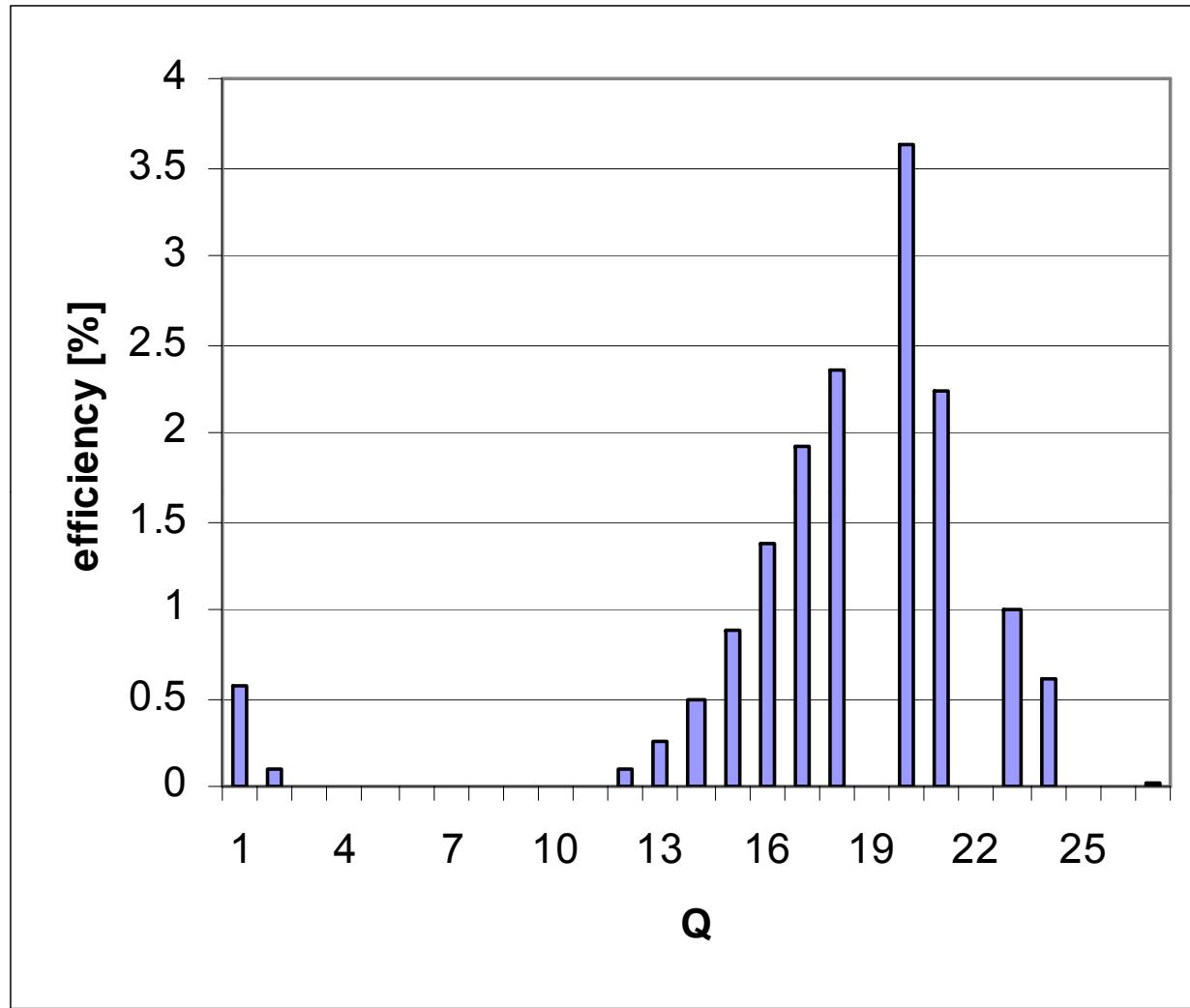
14.5 GHz ECR source PHOENIX from Panteknik
elements measured : Ar, Kr, Xe from ECR ion source
K, Rb, Cs from surface ion source

installation of the charge state breeder at ISAC





mass spectrum **with and without** Cs^+ injection (500 W rf power)



charge state distribution of Cs 15 nA Cs^{1+} injected
total efficiency >20%

charge breeder results from ISAC test stand

Measurements with ions from standard ISAC ion sources

Element	Mass	Charge state with maximum efficiency (A/Q)	Efficiency (%)	rise time (90%) for charge state with maximum efficiency (ms)	1+ ion source
Ar	40	8+ (5)	5.5	102	ECR
Kr	84	12+ (7)	6.3	401	ECR
Xe	129	17+ (7.6)	4.8	432	ECR
K	39	9+ (4.3)	2.1		surface
Rb	85/87	13+ (6.5)	3	230	surface
Cs	133	20+ (6.7)	3.5	300	surface + testsource

- emittance of Cs^{n+} measured $< 20 \pi \text{ mm mrad}$ @ 15q keV

ongoing developments

- EBIS/T

increase of electron beam current density

⇒higher capture efficiency
higher capacity
faster ionization

continuous mode operation

continuous injection, pulsed extraction at REXEBIS 2% for K¹⁰⁺

selective ionization by adaptation of electron energy

dielectronic recombination

J.R. Crespo Lopez-Urrutia et al. Rev Sci. Instr. 75 (2004) 1560

TESIS (tubular electron string ion source)

⇒high efficiency
pulsed and continuous mode operation possible
E.D. Donets et al. Rev Sci. Instr. 75 (2004) 1566

ongoing developments (cont.)

- ECRIS

- optimization of injection optics**

- ⇒higher capture efficiency**

- increase of rf frequency and / or 2 frequency heating**

- ⇒higher plasma density**

- capture efficiency**

- higher charge states**

- faster ionization**

- ultra high vacuum**

- ⇒smaller background from residual gas**

- higher charge states**

summary

	EBIS	ECRIS
state of the art	high charge states $A/q \approx 4$	medium charge states $A/q < 9$
	fast $\times 10$ ms	medium fast $\times 100$ ms
	efficient EBIS alone $\approx 20\%$	efficient $\approx 3-10\%$
	pulsed semi continuous mode	continuous beams only long pulses (ms @ 1 Hz)
	pure beams	high beam contamination
	intensity limitation 10^9 /s	high intensity 10^{12} /s
	pre bunching and cooling necessary	
goals for developments	higher capacity higher efficiency selective ionization	higher efficiency faster breeding lower beam contamination higher charge states

thank you



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